# Monthly LabAdviser/Process2Share update: 16/1 2015

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| Updated Subject  | Contributor | Link to the updated pages |
| **Overview of Sample processing**Exceptional good entry point to info about processes and tools. With new tables and pages that give an overview of DTU Danchip capabilities | **Jesper, Karen, Claus, Thomas and Berit @danchip** | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge#Overview_of_sample_processing> |
| **Introduction to LabManager**Added some information on how to use LabManager including links to presentations. | **Jesper Hanberg****@danchip** | <http://labadviser.danchip.dtu.dk/index.php/LabAdviser/Introduction_to_LabManager> |
| **Direct Structure Definition**New entry and comparison page on the possibilities for structuring your sample without having masking layer on the material you need to structure. Lithography methods are among these but also LASER micro machining, polymer Injection Molding and saw dicing. | **Jesper Hanberg and Claus Højgård Nielsen and Thomas Anhøj @danchip** | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Direct_Structure_Definition> |
| **Doping your wafer**New entry and comparison page on the possibilities for doping substrates and thin films with boron, phosphorous and Germanium | **Karen Birkelund @danchip** | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Doping> |
| **E-beam**Continuously adding new result with the CSAR e-beam resist | **Tine Greibe****@danchip** | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/CSAR> |
| **Pattern design and mask fabrication**Created section with link to details about pattern/mask design and fabrication. Moved old pages to this location and redesigned a bit. Info about Clewin5 use and mask design with e.g. location of alignment marks and how to order masks. | **Jesper Hanberg****@danchip** | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography#Pattern_Design_and_Mask_Fabrication> |
| **Updates on LASER page*** Average power measurement value for December 2014 (after 3D Micromac service).
* Fluence based on power measurement (with theoretical spot size).
* Laser pulse energy.
 | **Chantal Silvestre****@danchip** | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Back-end_processing/Laser_Micromachining_Tool> |
| **Customer meeting 2014**Adding the slides to the main page from the user meeting in December 2014 | **Anders M. Jørgensen** | <http://labadviser.danchip.dtu.dk/index.php/Main_Page> |
| **Wafer and sample drying**This page has been updated with comparison table and images. | **Karen Birkelund @danchip** | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Wafer_and_sample_drying> |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

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| **Manual for Hotplate (SU8)** |
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| **Manual for Developer TMAH Stepper.** |
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| **Manual for Spin dryer** |
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| **Manual for LPCVD Nitride Furnace (4")** |
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| **Manual for Electroplating-Ni (Technotrans microform.200)** |
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| **Manual for ASE** |
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| **Manual for KOH3 (4",6")** |
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| **Manual for Nitride etch** |
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| **Manual for IBE/IBSD Ionfab 300** |
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| **Manual for HF and BHF in various dedicated baths** |
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| **Manual for Isotropic Etch/Poly Etch** |
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| **Manual for DRIE-Pegasus** |
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| **Manual for 7-up 6"** |
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| **Manual for 7-up (Masks)** |
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| **Manual for Polymer Injection Molding** |
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| **Manual for FilmTek** |
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| **Manual for SEM Jeol** |
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| **User Manual for E-Beam writer 9500** |
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